RECEIVED
CENTRAL FAX CENTER
NUV 0 2 2006

Abstract

Disclosed herein is a wafer carrier locking device. The wafer carrier locking device includes a wafer carrier seated thereon a plurality of wafers. A main equipment executes a semiconductor manufacturing process. An auxiliary equipment includes a carrier sensor to detect a scated state of the wafer carrier relative to a base member, a wafer sensor to detect a number and positions of the wafers seated on the wafer carrier, and the base member having a plate shape. A locking unit is provided at a front portion of the base member to prevent the wafer carrier from being undesirably moved.